

DOCKET NO: 236664US-2RE

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

Nobuo ISHII, et al. : GROUP ART UNIT:

ORIGINAL PATENT NO: 6,265,031

ISSUED: JULY 24, 2001

FOR: METHOD FOR PLASMA  
PROCESSING BY SHAPING  
AN INDUCED ELECTRIC FIELD

PRELIMINARY AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Prior to examination on the merits, please amend the above-identified patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.

A separate statement regarding the status of the claims, as required by 37 CFR 1.173(c), is found on page 8 of this paper.

A separate statement support for the new claims, as required by 37 CFR 1.173(c), is found on page 9 of this paper.